Page 1 of 2

INFORMATION DISCLOSURE STATEMENT Atty. Docket No.: 110.0142 0101

Applicant(s): ZHAN et al.

Application Filing Date: 18 October 2000

Information Disclosure Statement mailed: March 9, 2004

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U.S. PATENT DOCUMENTS

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A C	mer Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
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	lor	5,220,403	06/15/93	Batchelder et al.			
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Up	Azzam, "Differential reflection phase shift under conditions of attenuated internal reflection," J. Opt. Soc. Am. A, 1999;16(7):1700-1702.
m	Bu-Abbud et al., "Characterization of Fabrication Damage in SrTiO ₃ by Internal and External Measurements," <i>Surface Science</i> , 1980;96:329-345.
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m	Ikeda et al., "Molecular orientation near the surface of a smectic liquid crystal cell showing V-shaped switching by means of attenuated total internal reflection ellipsometry," <i>Physical Review E</i> ; 2001;63:061703-1-7.
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STATEMENT

Atty. Docket No.: 110.0142 0101	Serial No.: 09/691,006			
Applicant(s): ZHAN et al.	Confirmation No.: 4510			
Application Filing Date: 18 October 2000	Group: 2877			
Information Disclosure Statement mailed:	March 9, 2004			

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	Examine Initials	Document Description					
TF	MP	Johansen et al., "Imaging surface plasmon resonance sensor based on multiple wavelengths: Sensitivity considerations," <i>Review of Scientific Instruments</i> , 2000;71(9):3530-3538.					
	M	Moy, "Immersion ellipsometry," Applied Optics, 1981;20(22):3821-3822.					
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INFORMATION DISCLOSURE STATEMENT

Atty. Docket No.: 110.0142 0101	Serial No.: 09/691,006		
Applicant(s): ZHAN et al.	Confirmation No.: 4510		
Application Filing Date: 18 October 2000	Group: 2877		
Information Disclosure Statement mailed:	november 7, 2003		

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Initial							Yes	No
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conformance and not considered. Include copy of this form with next communication to applicant.